



SHEET 1 OF 1

Substitute for forms 1449A/PTO & 1449B/PTO

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Oliver KIENZLE et al.FILING DATE
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Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
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Examiner Signature	ZIA R. HASHMI	Date Considered	5/25/05
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